



Docket No.: H6808.0032/P032  
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:  
Shuichi Takeuchi, et al.

Examiner: Kalimah Fernandez

Application No.: 10/750,838

Art Unit: 2881

Filed: January 5, 2004

For: SCANNING ELECTRON MICROSCOPE  
AND SAMPLE OBSERVING METHOD  
USING IT

**AMENDMENT**

Commissioner for Patents  
MS: Amendment  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This paper is in response to the Office Action dated October 5, 2004. Please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 11 of this paper.